

# PECVD Grown Graphene as Transparent Electrode in GaN-based LEDs

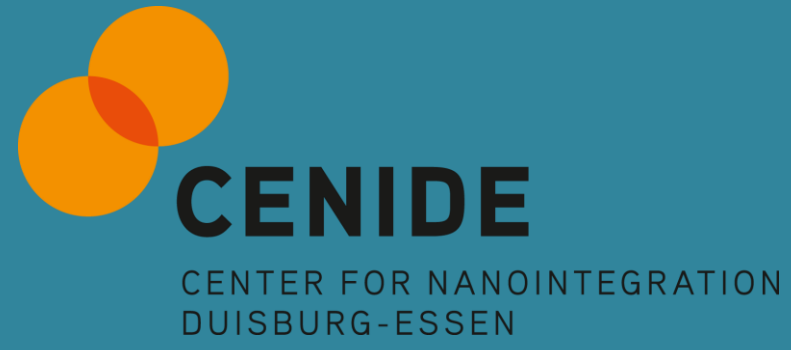
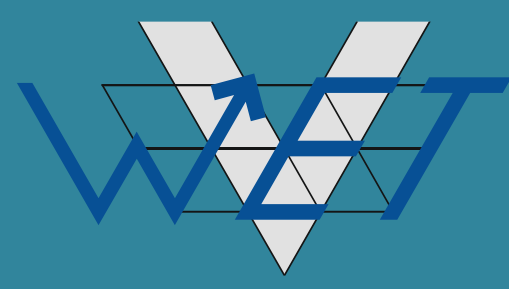
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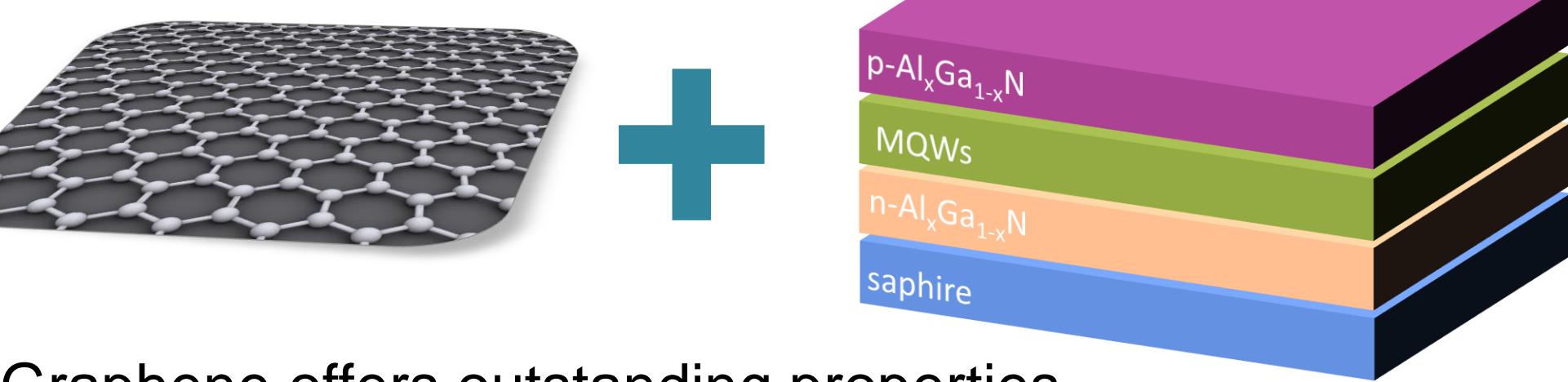


## Motivation

**Direct growth of graphene on GaN via plasma-enhanced chemical vapor deposition (PECVD) without H<sub>2</sub> atmosphere**

### Idea

Use graphene as transparent electrode to increase lateral current spreading of GaN-based LEDs



Graphene offers outstanding properties

➤ High **charger carrier mobilities** (200.000 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup>) [1]

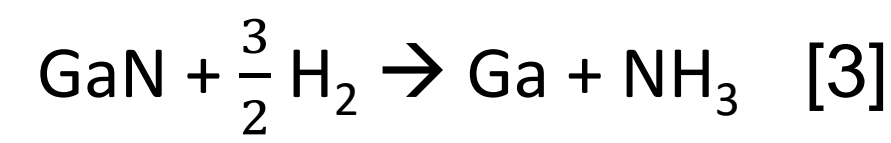
➤ High optical **transparency** (2.3% absorption per layer) [2]

Using graphene as a transparent electrode on GaN-based LEDs

### Challenge

Transfer-free processing of graphene directly on Al<sub>x</sub>Ga<sub>1-x</sub>N LEDs without the use of H<sub>2</sub>

➤ "Reverse Epitaxy" destroys GaN surface under H<sub>2</sub> rich atmosphere and high temperatures

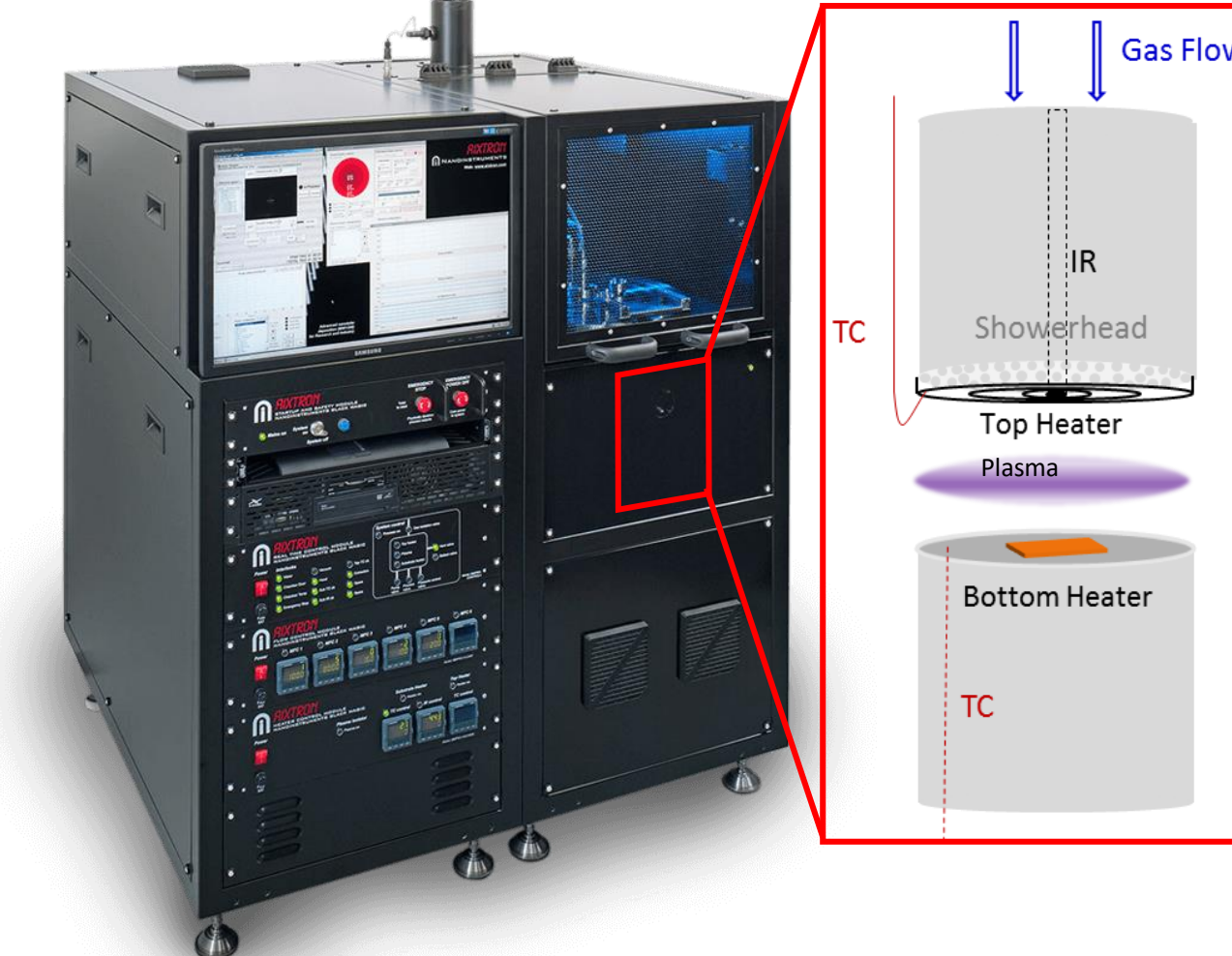


➤ N<sub>2</sub> is known to protect the GaN surface under elevated temperatures [4]

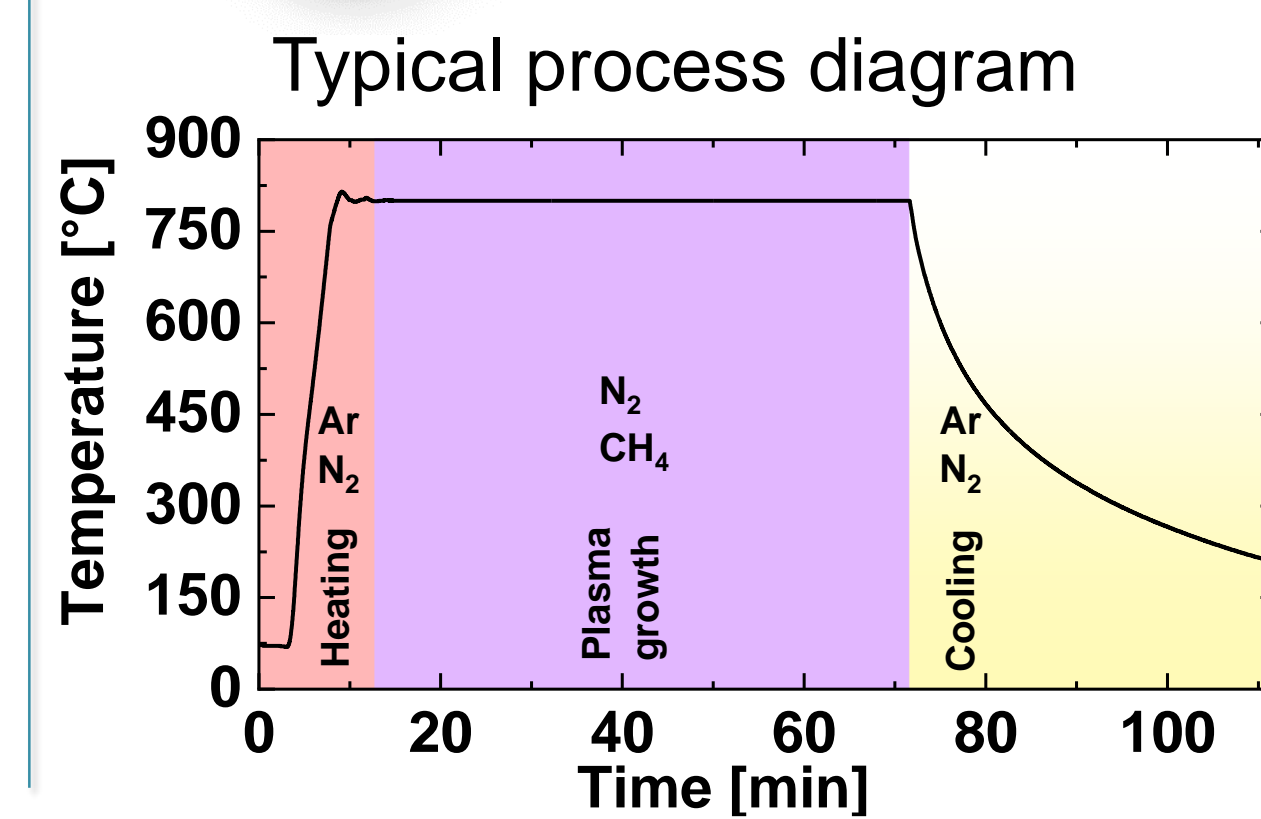
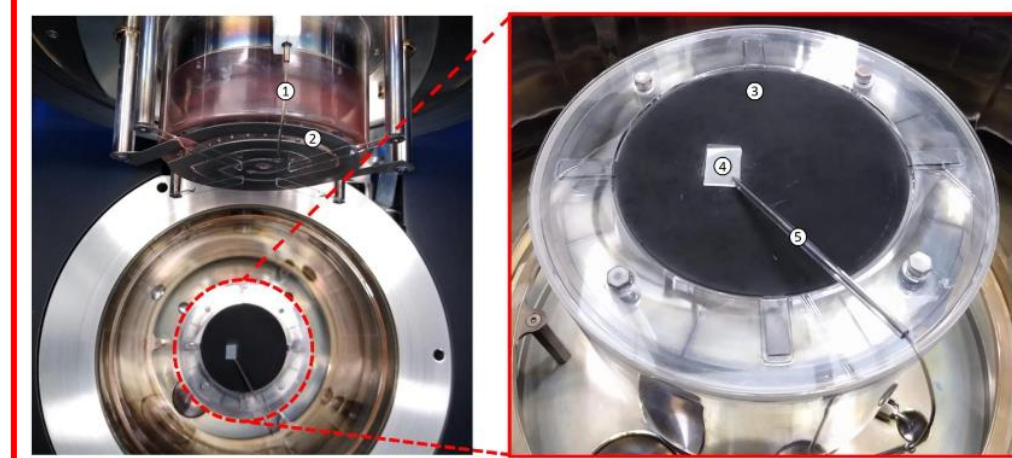
Idea: Switch from commonly used H<sub>2</sub> to N<sub>2</sub> during graphene growth process

## PECVD System

**AIXTRON Black Magic 4"**

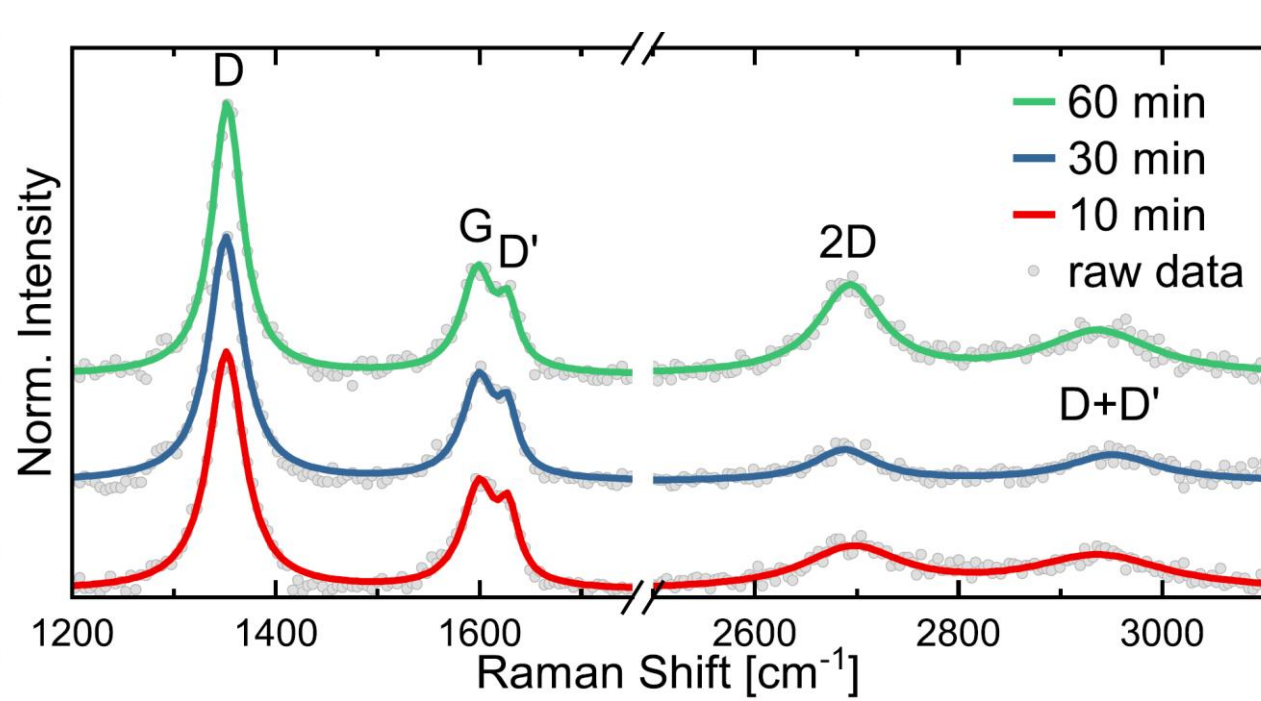
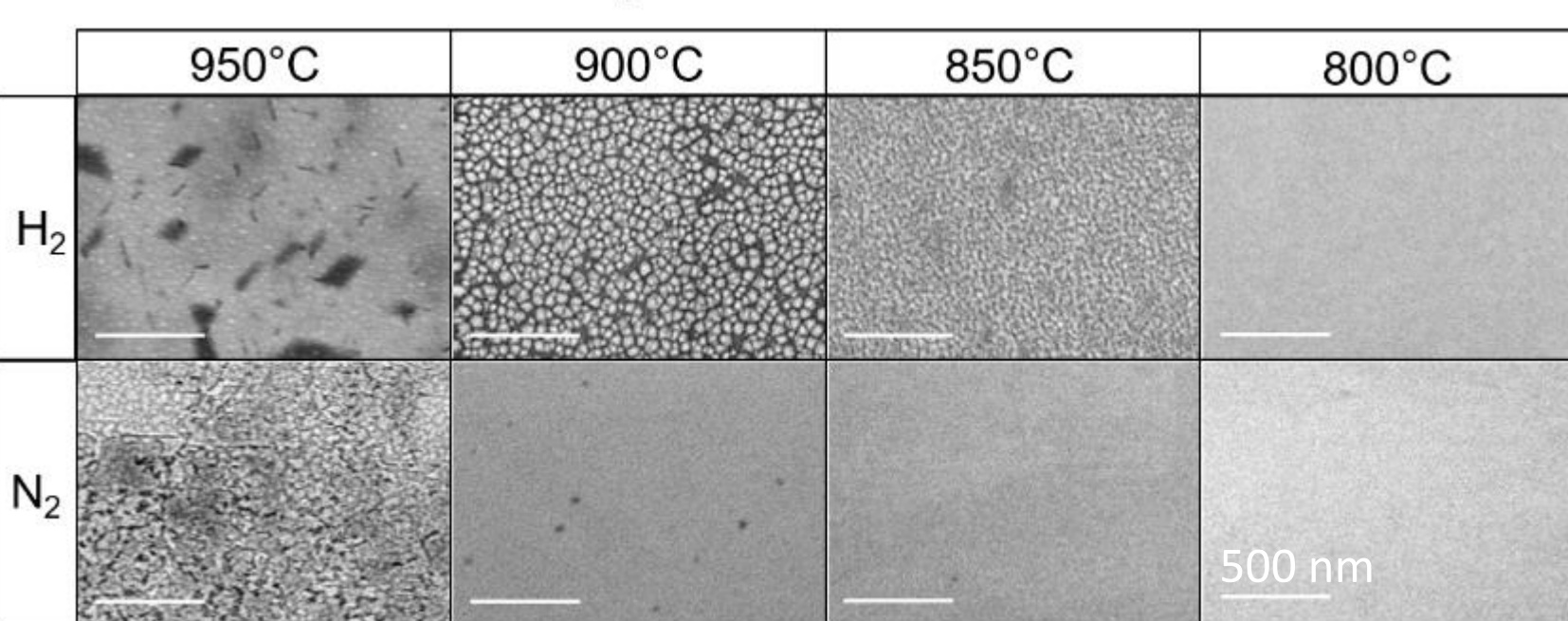


View into the inner chamber



- **Homogeneous** gas flow through the showerhead
- Temperature control over the bottom and top heater (>1000 °C)
- **Pulsed DC plasma** operation with variable frequency (1-100 kHz possible)

## H<sub>2</sub> vs. N<sub>2</sub> atmosphere [5]

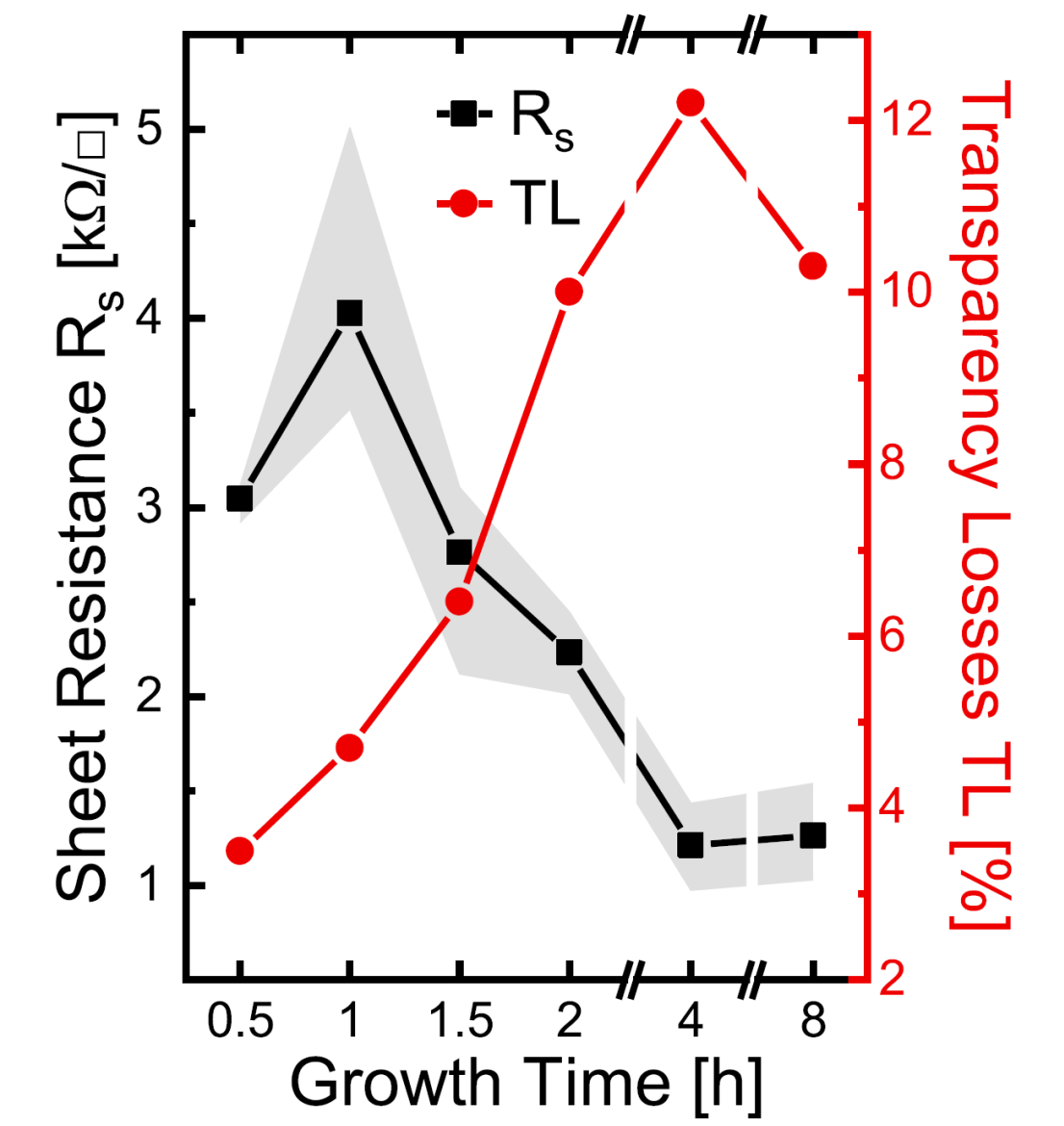
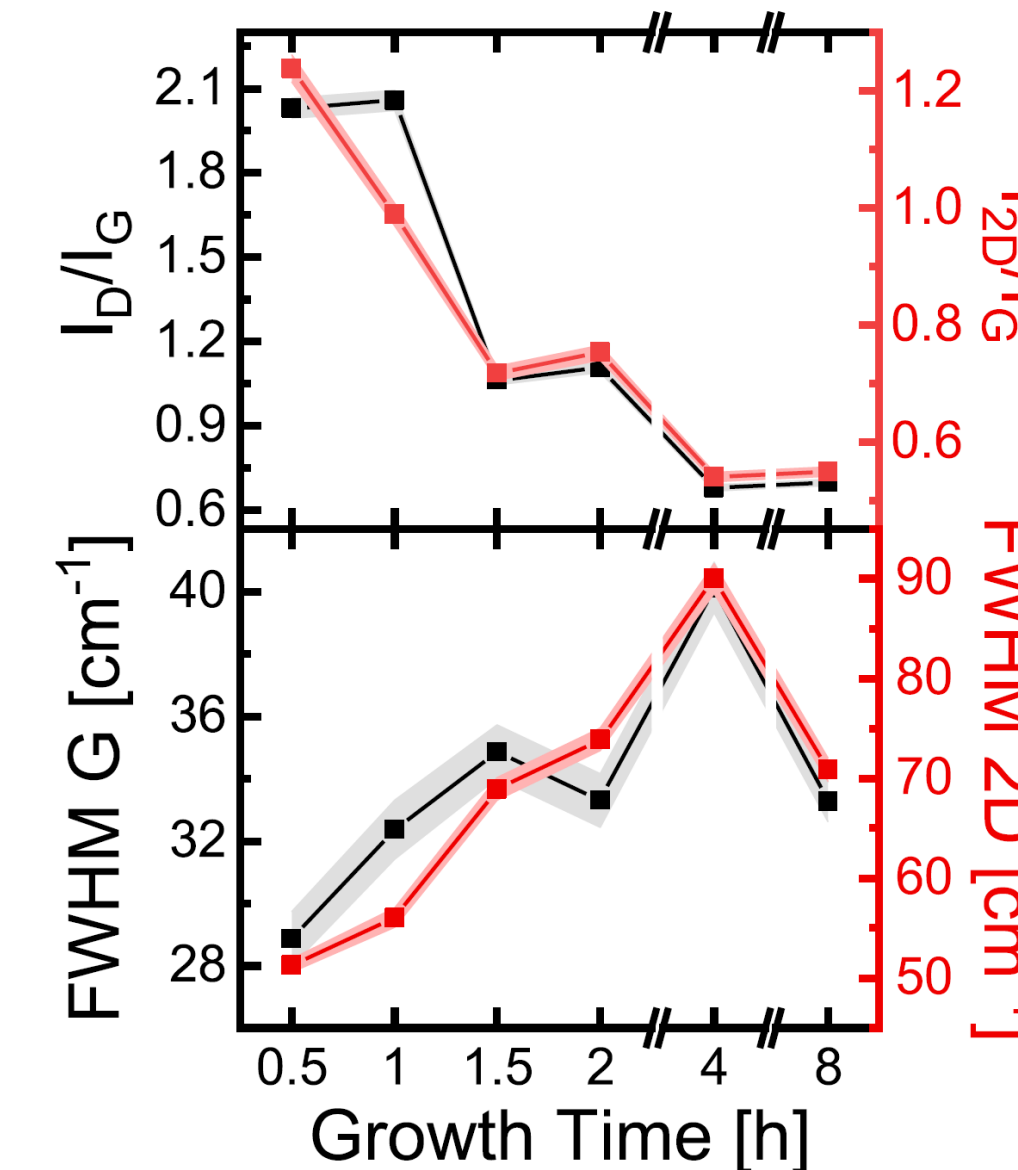
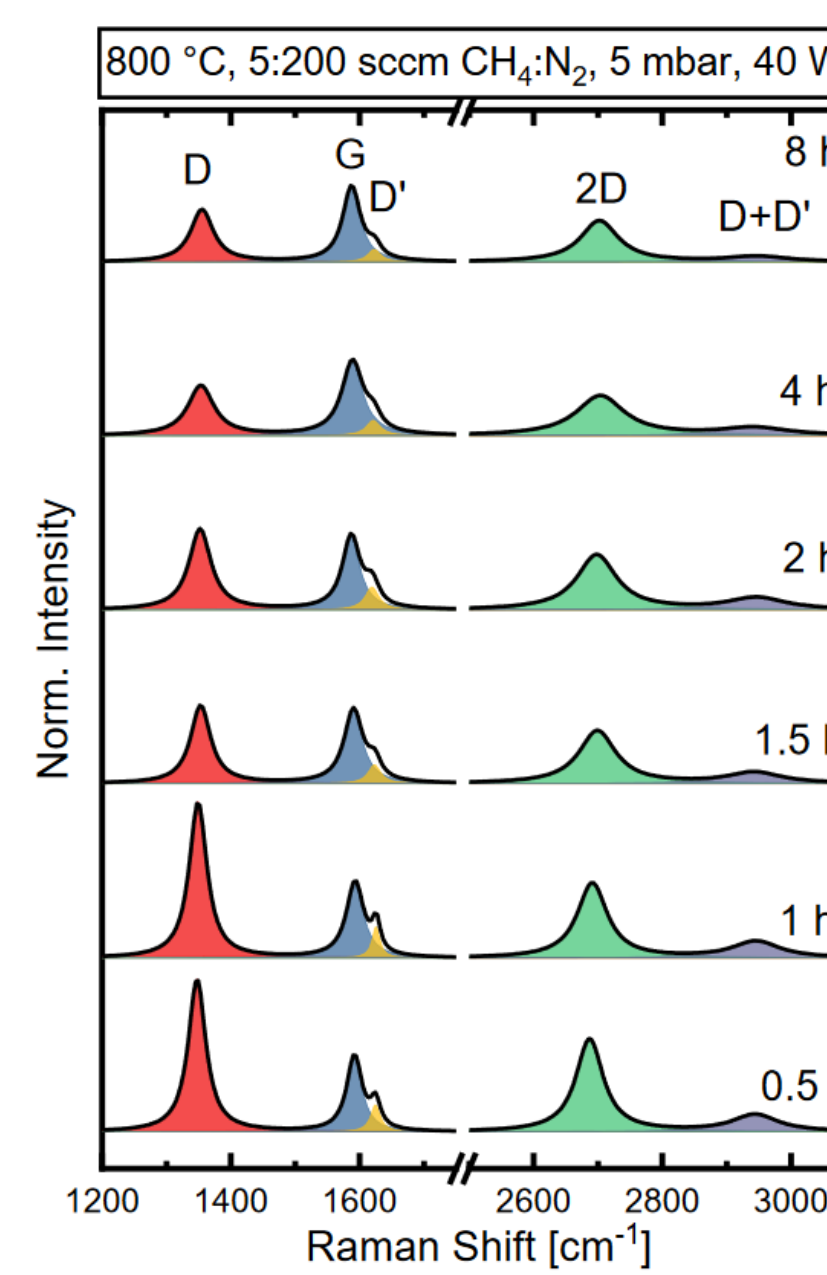


- H<sub>2</sub> atmosphere shows **distinctive etching** of the GaN surface even at lower temperatures
- **No graphene growth** can be observed
- Switching to N<sub>2</sub> atmosphere **protects the GaN surface** from etching effects

- **Graphene growth** under N<sub>2</sub> atmosphere observed
- **Increasing 2D-peak** with increasing growth time

N<sub>2</sub> atmosphere shows promising results in protecting the GaN surface while simultaneously supporting graphene growth

## Growth time is crucial [5]



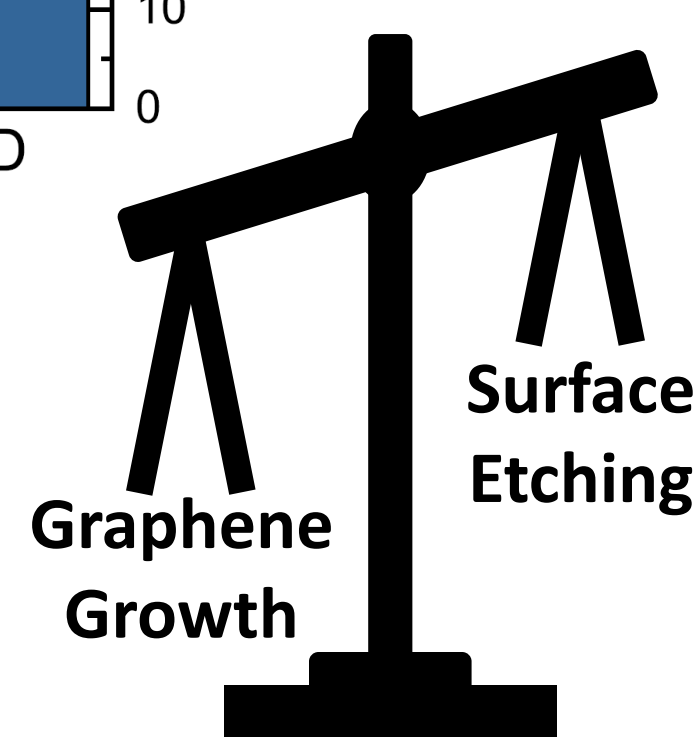
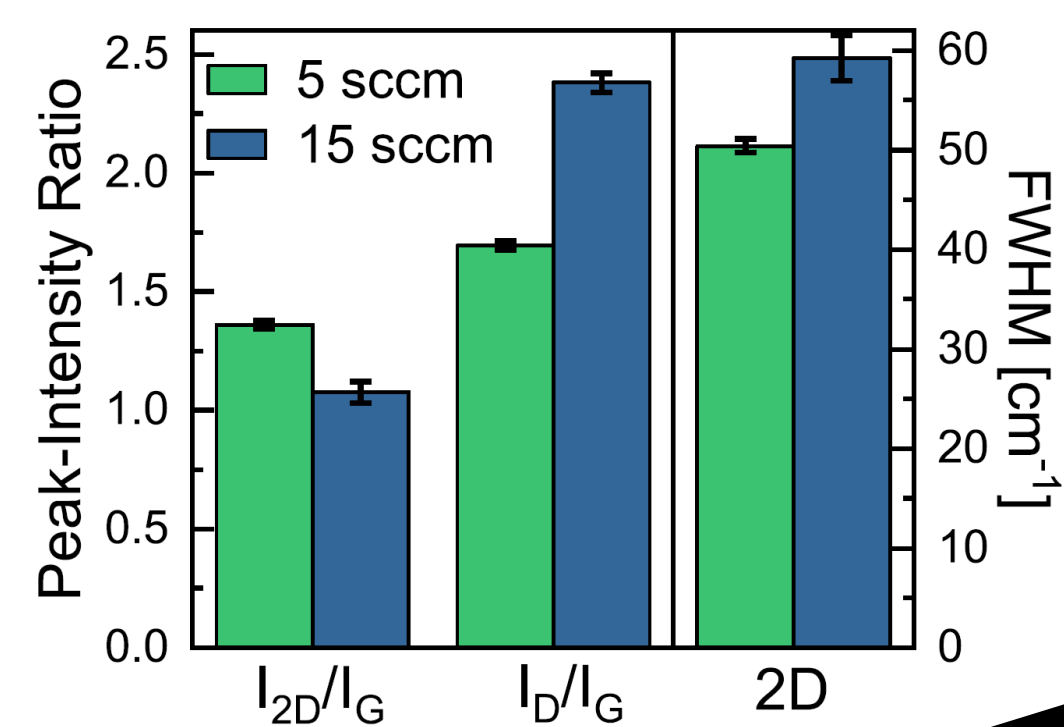
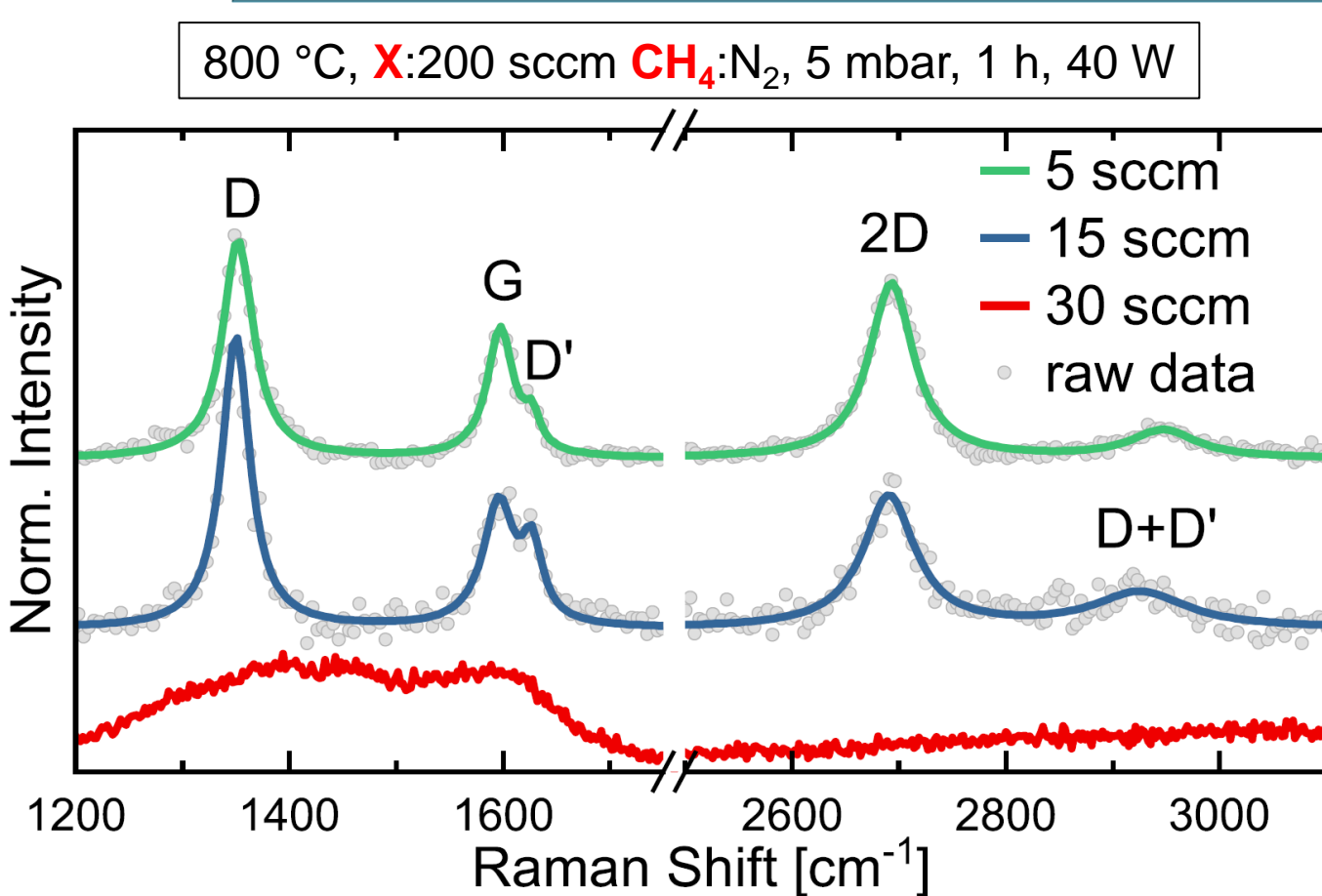
With increasing growth time

- **Decrease** of I<sub>D</sub>/I<sub>G</sub> & I<sub>2D</sub>/I<sub>G</sub> ratios
- **Increase** in FWHM of G & 2D peaks

Growth of multilayer graphene with increasing growth time  
→ Tuning of the sheet resistance of the grown graphene layers

Sheet resistances of ~1 kΩ/□ @ ~12% transparency losses

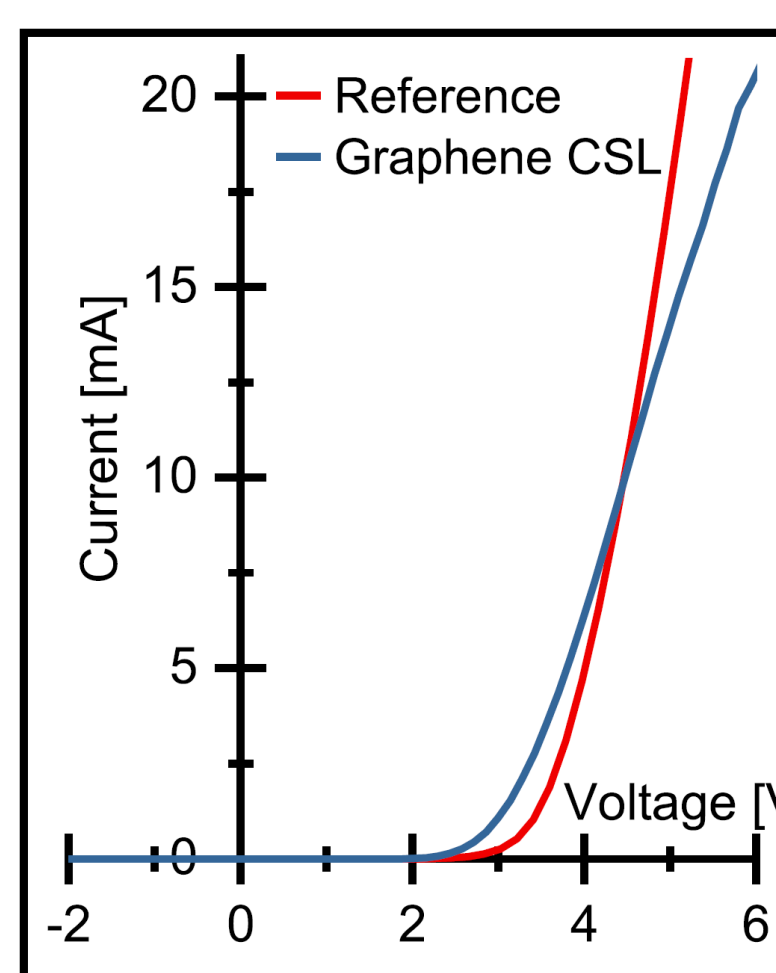
## Influence of the CH<sub>4</sub> amount [5]



- High CH<sub>4</sub> amount lead to distinctive **etching** of the GaN surface due to free H species
- 5 sccm to 200 sccm CH<sub>4</sub>:N<sub>2</sub> offers a **good growth/etch balance** for graphene growth
- I<sub>2D</sub>/I<sub>G</sub> ratios of > 1.5 achieved

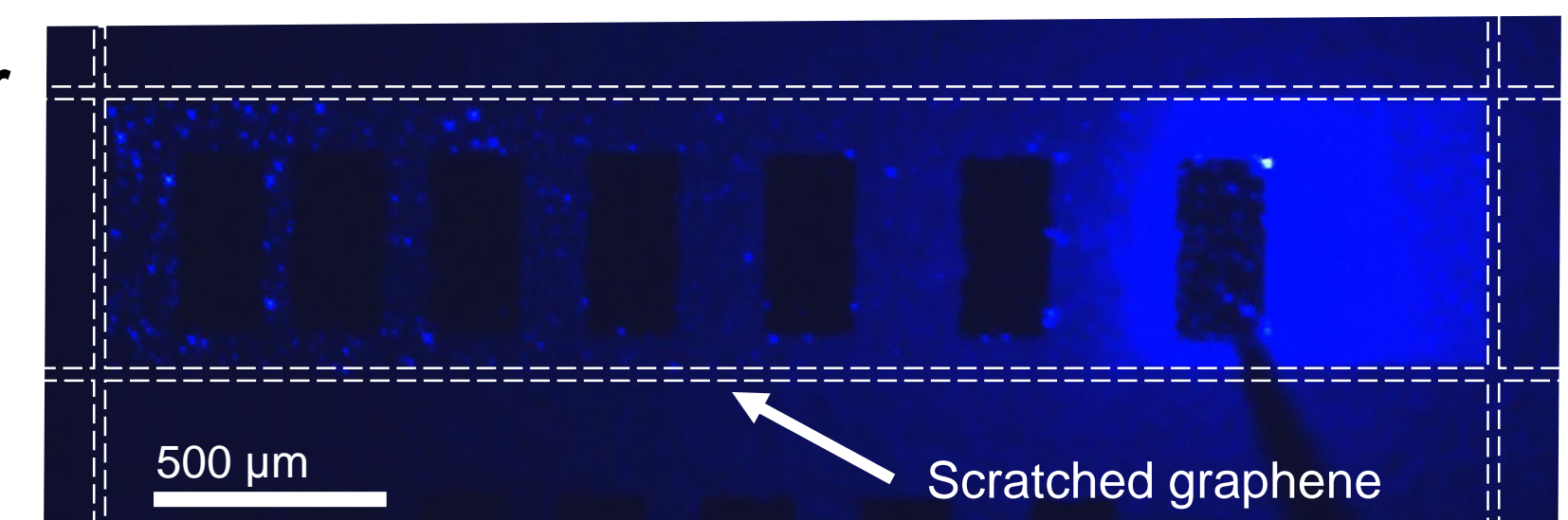
CH<sub>4</sub>:N<sub>2</sub> ratio influences the balance between graphene growth and surface etching

## So does it work as intended? [5]



➤ **Diode-like behavior** after growth process

- **~8 times higher emission** around contact area compared to LEDs without graphene

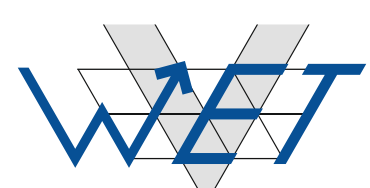


Graphene electrode shows largely increased emission area across the LED surface

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### REFERENCES

- [1] K.I. Bolotin *et al.*, *Solid State Comm.* **146** (2008) 351-355
- [2] R.R. Nair *et al.*, *Science* **320** (2008) 1308
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